





The GL8 CLIV Gen2 is GermanLitho's latest semi-automatic, full-field, high-resolution UV nanoimprint equipment. The proprietary CLIV (Contact Litho into Vacuum) technology guarantees the accuracy and replication fidelity of imprinted structures. The GL8 CLIV Gen2 enables semi-automatic imprinting of high resolution (higher than 10mm*) and high-aspect-ratio (greater than 10: 1*) nanostructures on up to 200mm wafers. The equipment supports automatic replication of flexible composite working stamps, allowing high resolution and a long service life, as well as significantly reducing the cost of large-area molds in nanoimprint processes. The GL8 CLIV Gen2 is suitable for R&D and pilot production of DOEs, AR / VR waveguides (including slanted gratings), WGPs, metalenses, biochips, LED PSSs, MLAs and other applications.

GL8 CLIV Gen2

200mm High-resolution UV nanoimprint lithography equipment

Technical Data

Substrate size	2inch, 100mm, 150mm, 200mm (Special sizes can be customized)
Substrate material	Silicon, glass, quartz, plastic, metal, etc.
Wafer loading & unloading	Single wafer automatic loading and unloading
Wafer pre-alignment	Optical pre-alignment
Supported NIL process	UV-NIL with GermanLitho proprietary CLIV (Contact Litho into Vacuum) technology guarantees the accuracy of imprinted structures and replication fidelity.
Resolution	Higher than 10 nm*
Aspect ratio	Greater than 10:1*
Residual layer thickness (RLT)	Less than 10nm*
UV curing light source	High power UV LED panel light source (365nm, light intensity >1000mW/cm², water cooling, (2000mw/cm² optional)
Mini-environment and climate control	Standard, external environment class 100, internal environment better than class 10*
Automatic imprinting	Supported
Automatic separation	Supported
Automatic working stamp replication	
Automatic alignment	Optional

- Parameters depend on the mold, material, process and operating environment, not equipment limits
- * GermanLitho reserves the right to interpret the information

Features

- Volume-proven full-filed nanoimprint equipment for high-resolution, high-aspect-ratio nanostructures on up to 200mm wafers.
- CLIV imprinting technology guarantees the accuracy and replication fidelity of imprinted structures.
- Automatic internal replication of flexible composite working stamp, reducing the cost of large-area molds in nanoimprint processes.
- Fully-automatic nanoimprinting processes including working stamp replication, alignment, imprinting, curing and separation.
- High power UV LED panel (365nm, light intensity >1000mW/cm²) with water cooling, light sources of different power and wavelength can be provided according to customer specifications, perfectly supporting a variety of commercial nanoimprint materials.
- High power UV LED panel light source (365nm, light intensity >1000mW/cm²) with water cooling, possible customization of power and wavelength of the light source, perfectly support a variety of commercial nanoimprint materials.
- Mini-environment and electrostatic elimination device equipped as standard.
- Based on our experiences, we have created nanoimprint process and material starter-kits to be delivered with our products, enabling our customers to immediately make use of the world-leading level of nanoimprint technology.



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